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FOR IMMEDIATE RELEASE

**ISSYS Inc. Awarded New Patent for Micromachined Smart Filter**

Ypsilanti, MI December 3, 2003 –Integrated Sensing Systems, Inc. (ISSYS) announced that the U.S. Patent Office has granted it a device and method patent (US 6,637,257) entitled “Micromachined Fluid Analysis Device and Method.”

This patent represents a new way of performing fluid analysis by separating cells and/or particles from a fluid. The device is a micromachined filter with electrodes patterned across the sieve surface. As debris is trapped a change in the electrical signal indicates the type and density of the matter on the filter. Applications exist in urology, blood analysis and industrial and vehicular lubricants and fuel.

Dr. Douglas R. Sparks, ISSYS Executive Vice President stated “This new technology can be coupled with other MEMS sensors and applied in fields as widely divergent as urology for sensing leukocytes or to motor oil quality sensors to detect metal particles due to engine wear. This wide applicability is an indication of the significance of this new device.”

**Company Background:** ISSYS is a leader in advanced micromachining technologies for medical devices, microfluidic and scientific analytical sensing applications. Founded in 1995 by world-renowned leaders in MEMS technology, ISSYS is one of the oldest independent MEMS companies in the US and has been offering MEMS services longer than any other company in the US. ISSYS operates a “full manufacturing under one roof,” multi-million-dollar, state-of-the-art Bio-MEMS fabrication facility located near Ann Arbor, Michigan. ISSYS offers a high level of quality control standards required by invasive medical products (targeting FDA-compliant manufacturing and European Medical Device Manufacturing -- EN 4600 --, as well as ISO 9000). ISSYS is a vertically integrated company dedicated to developing and manufacturing system-level products based on MEMS technology (MEMS Inside). For more company, product and service information, please visit <http://www.mems-issys.com/>

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